



SEMICONDUCTOR



GENERAL  
VACUUM



ANALYTICAL  
INSTRUMENTS



R&D



EV-SA

# THE ANALYTICAL ONE

Air cooled EV-SA dry vacuum pump  
for clean vacuum applications



The EV-SA has an excellent performance for light duty applications. The energy consumption is significantly reduced. The operation cost is very low and the footprint small. A powerful solution with high ROI rate. Small but strong.

## BENEFITS

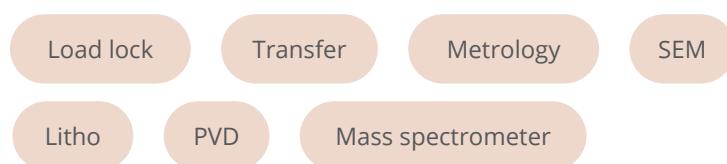
- Lowest energy consumption
- No maintenance
- Low operation costs
- Wide vacuum range
- High profitability
- Minimal footprint



Models		EV-SA20	EV-SA30
Max pumping speed in l/min		1,670	3,300
Max pumping speed in m³/h		100	200
Ultimate pressure Pa Gas ballast: on		5.0	3.0
Power at ultimate Pressure in kW		0.45	0.45
Cooling requirements		air cooling	
Noise emission dB(A)		57	60
Size in mm	L	584	713
	W	324	356
	H	347	347
Weight in kg		65	90
Application form			

All data without guarantee.

## APPLICATIONS FOR EV-SA



## APPLICATIONS RANGE



**For further information, technical data or drawings please contact  [components@ebarapm.eu](mailto:components@ebarapm.eu)**

EBARA is a worldwide leading global manufacturer of vacuum and semiconductor systems used in the production of wafers, liquid crystals, solar cells and other products requiring advanced technology.

EBARA supports



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EBARA Precision Machinery Europe (EPME) is part of the Japanese EBARA Group and employs more than 200 people in Europe. The portfolio includes dry and turbo molecular vacuum pumps as well as gas abatement systems. In addition, EPME sells state-of-the-art CMP tools, wafer bevel polishing and substrate coating systems. In Europe, EPME has a central warehouse and two overhaul centres for vacuum pumps. EBARA is No 2 on the vacuum pumps and CMP tools world market and No 1 on the Wafer Bevel Polisher world market.

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